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(12) **United States Design Patent**  
**Sasaki et al.**

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(54) **ELECTROSTATIC CHUCK FOR SEMICONDUCTOR MANUFACTURING EQUIPMENT**

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(30) **Foreign Application Priority Data**

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(51) **LOC (10) Cl.** ..... **13-03**

(52) **U.S. Cl.**  
USPC ..... **D11/182**

(58) **Field of Classification Search**  
USPC ..... D13/182; D15/140  
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21/683; H01L 21/6831; H01L 21/6833;  
H01L 21/6835; H01L 21/68; H01L 21/67;  
B23Q 3/15; B23Q 3/154; B23Q 3/1543;  
B23Q 3/1546; B23B 31/28; G03F  
7/70708; G03F 7/707; H02N 13/00;  
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See application file for complete search history.

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(57) **CLAIM**

The ornamental design for an electrostatic chuck for semiconductor manufacturing equipment, as shown and described.

**DESCRIPTION**

FIG. 1 is a front view of an electrostatic chuck for semiconductor manufacturing equipment, showing our new design;

FIG. 2 is a rear view thereof;

FIG. 3 is a top plan view thereof;

FIG. 4 is a bottom plan view thereof;

FIG. 5 is a right side view thereof;

FIG. 6 is a left side view thereof;

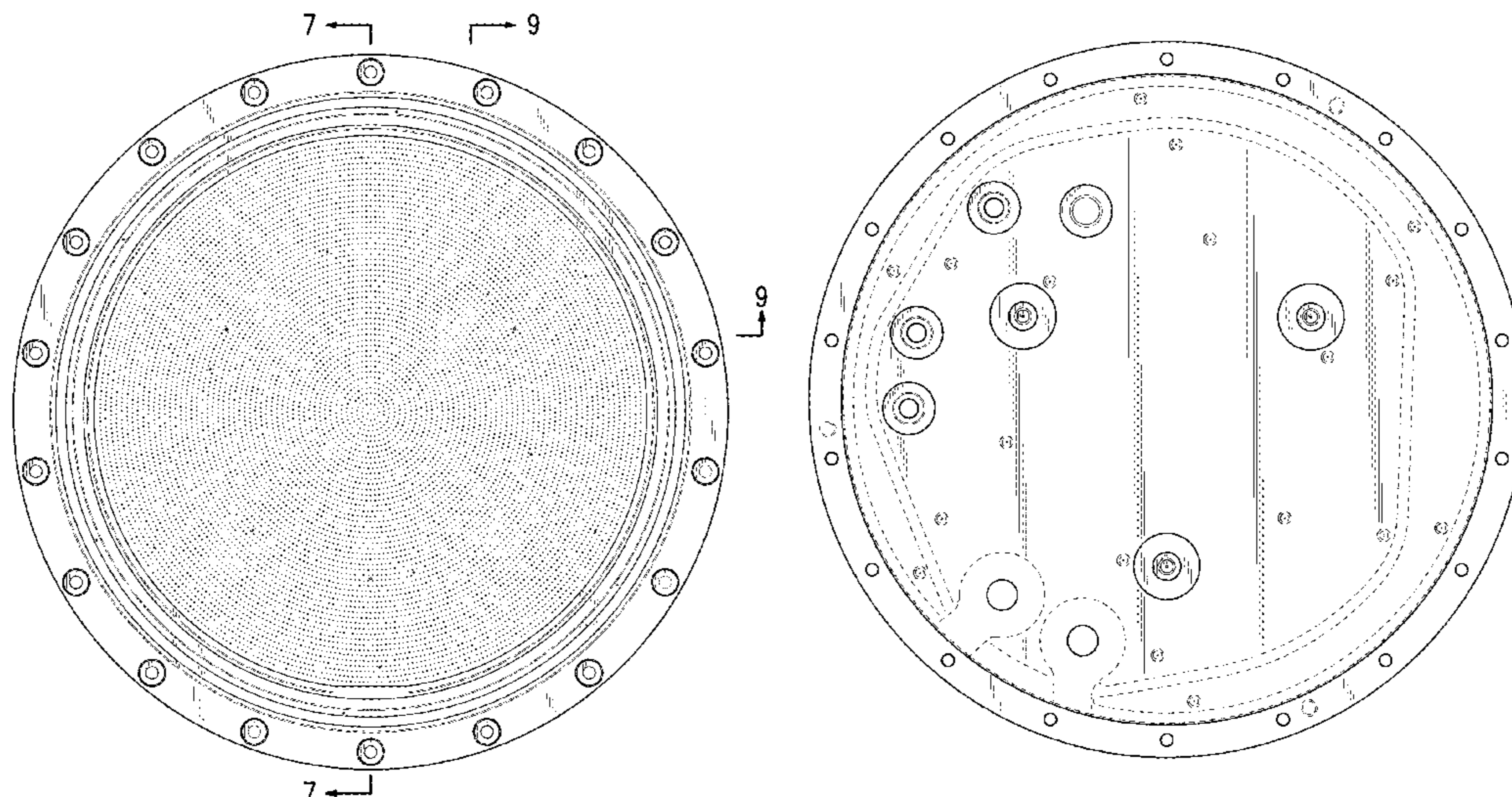
FIG. 7 is a cross sectional view taken along the lines of 7-7 of FIG. 1;

FIG. 8 is an enlarged view of a portion taken along lines of 8-8 of FIG. 7; and,

FIG. 9 is an enlarged view of a portion taken along lines of 9-9 of FIG. 1.

The features shown in broken lines depict environmental subject matter only and form no part of the claimed design.

**1 Claim, 9 Drawing Sheets**



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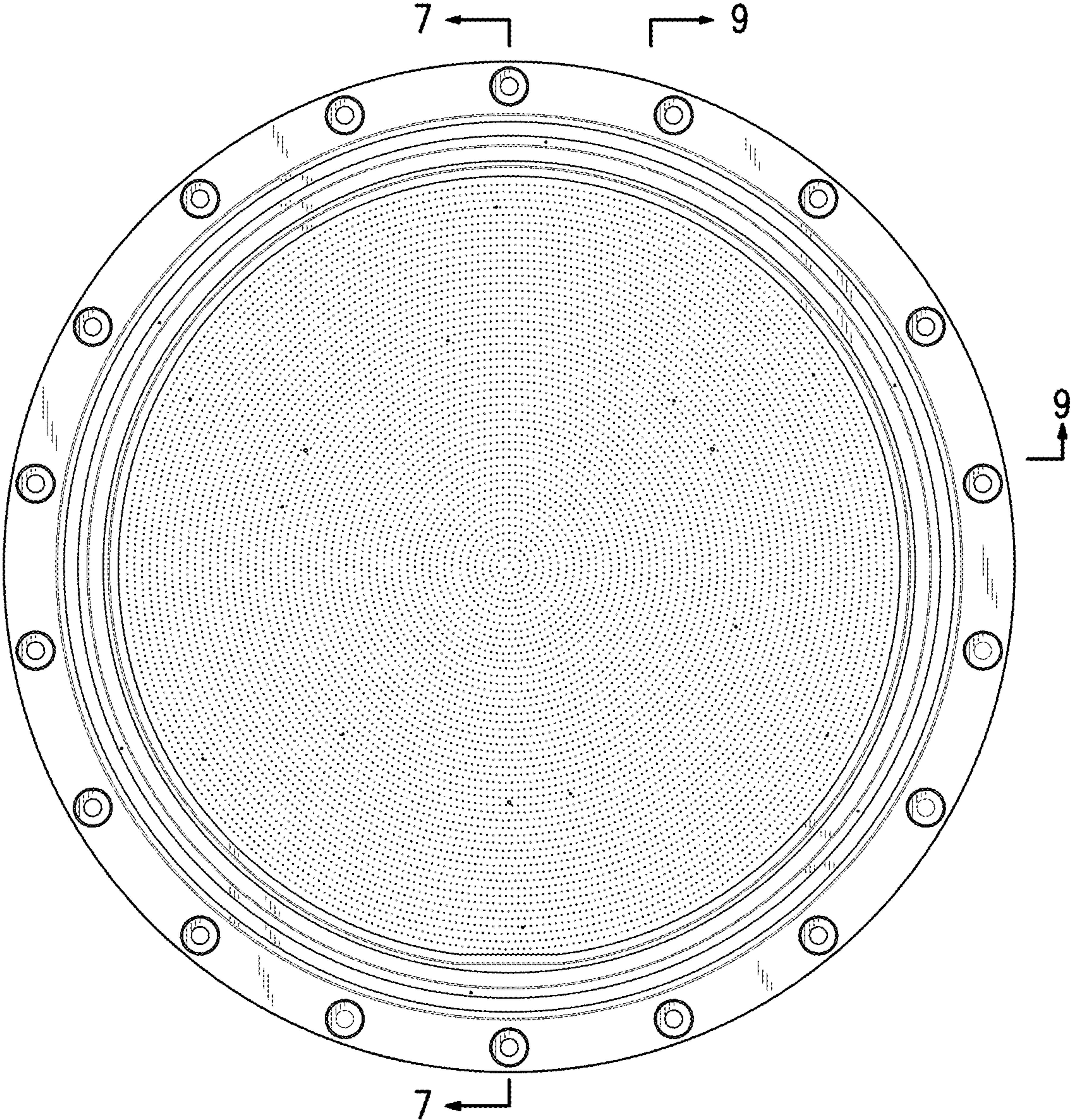


FIG. 1

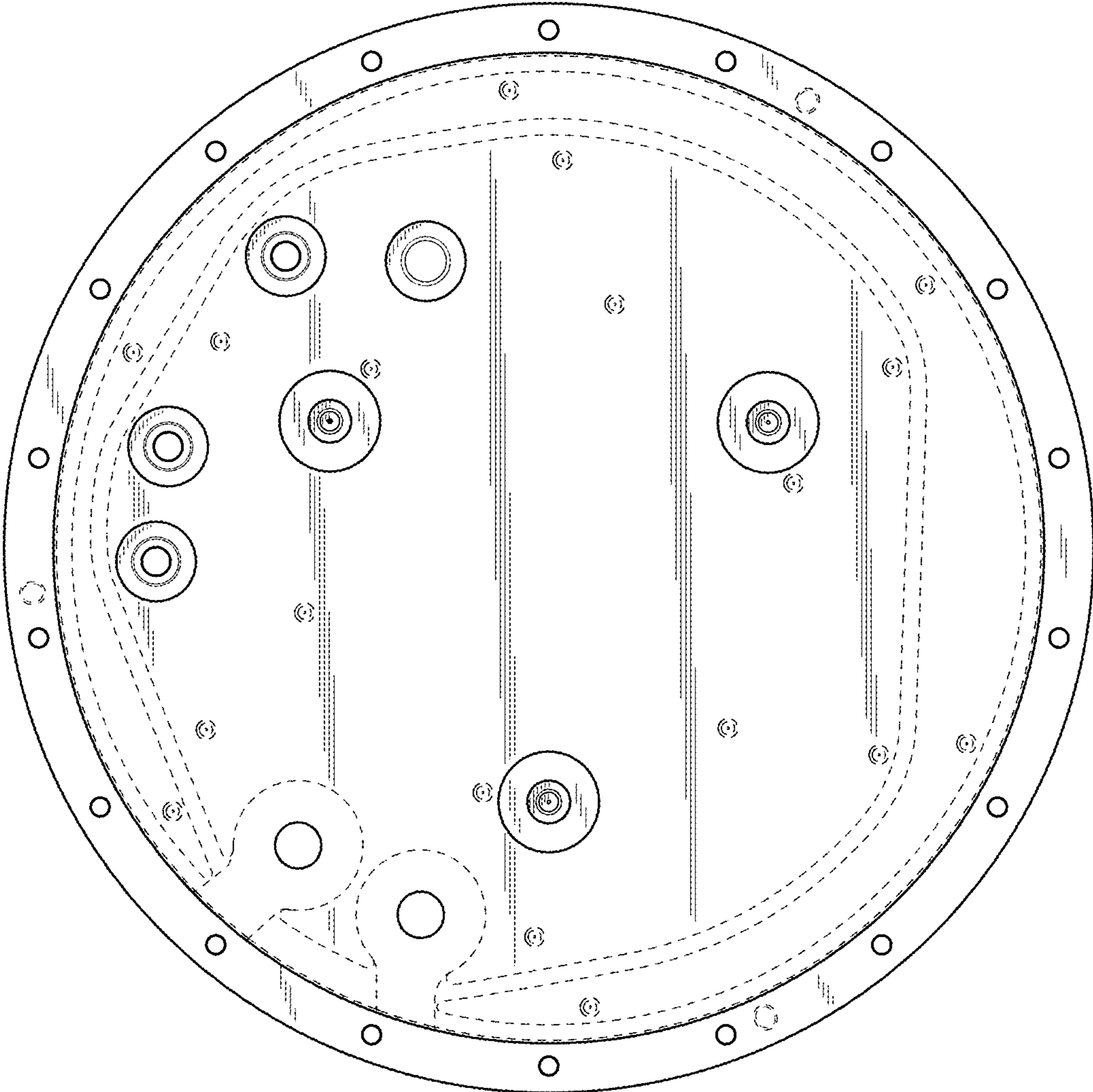


FIG. 2

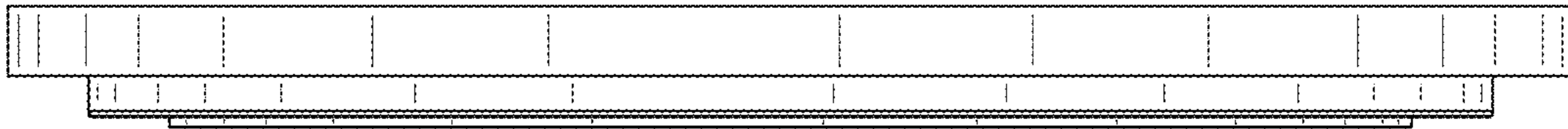


FIG. 3

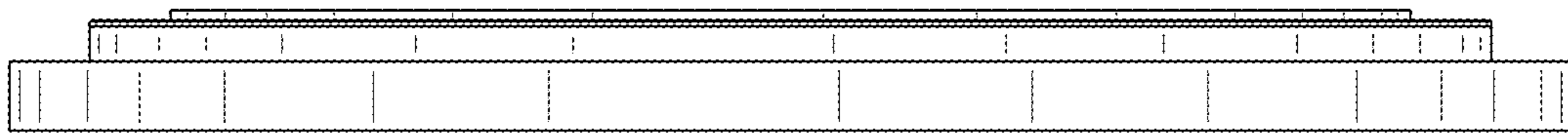


FIG. 4

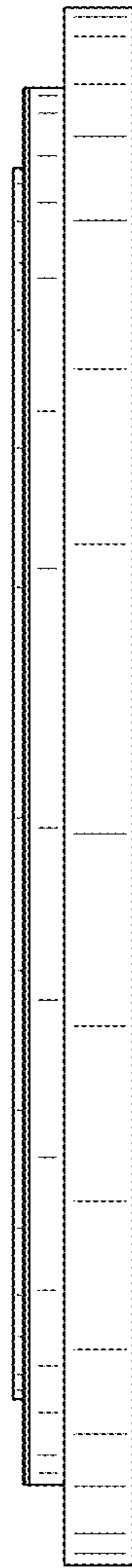


FIG. 5

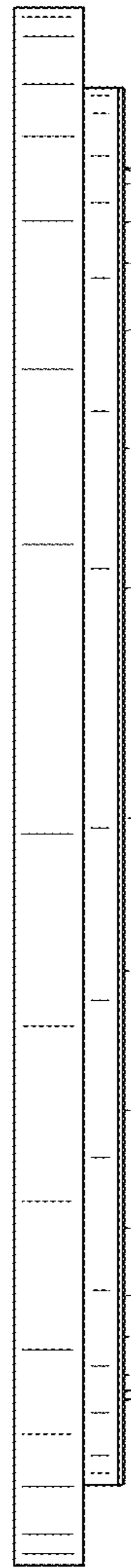


FIG. 6



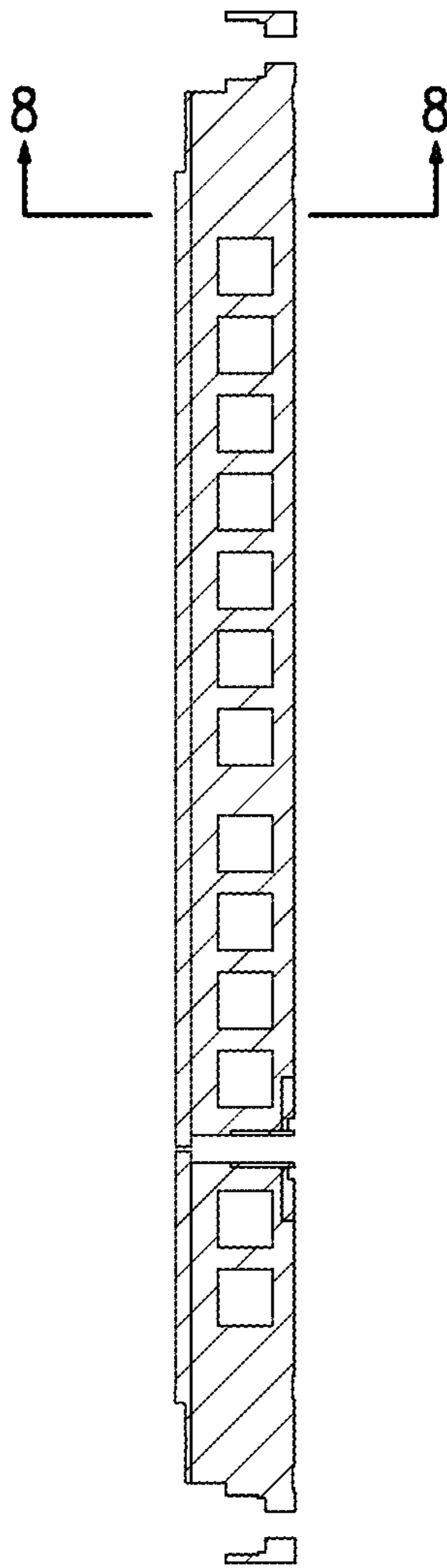


FIG. 7

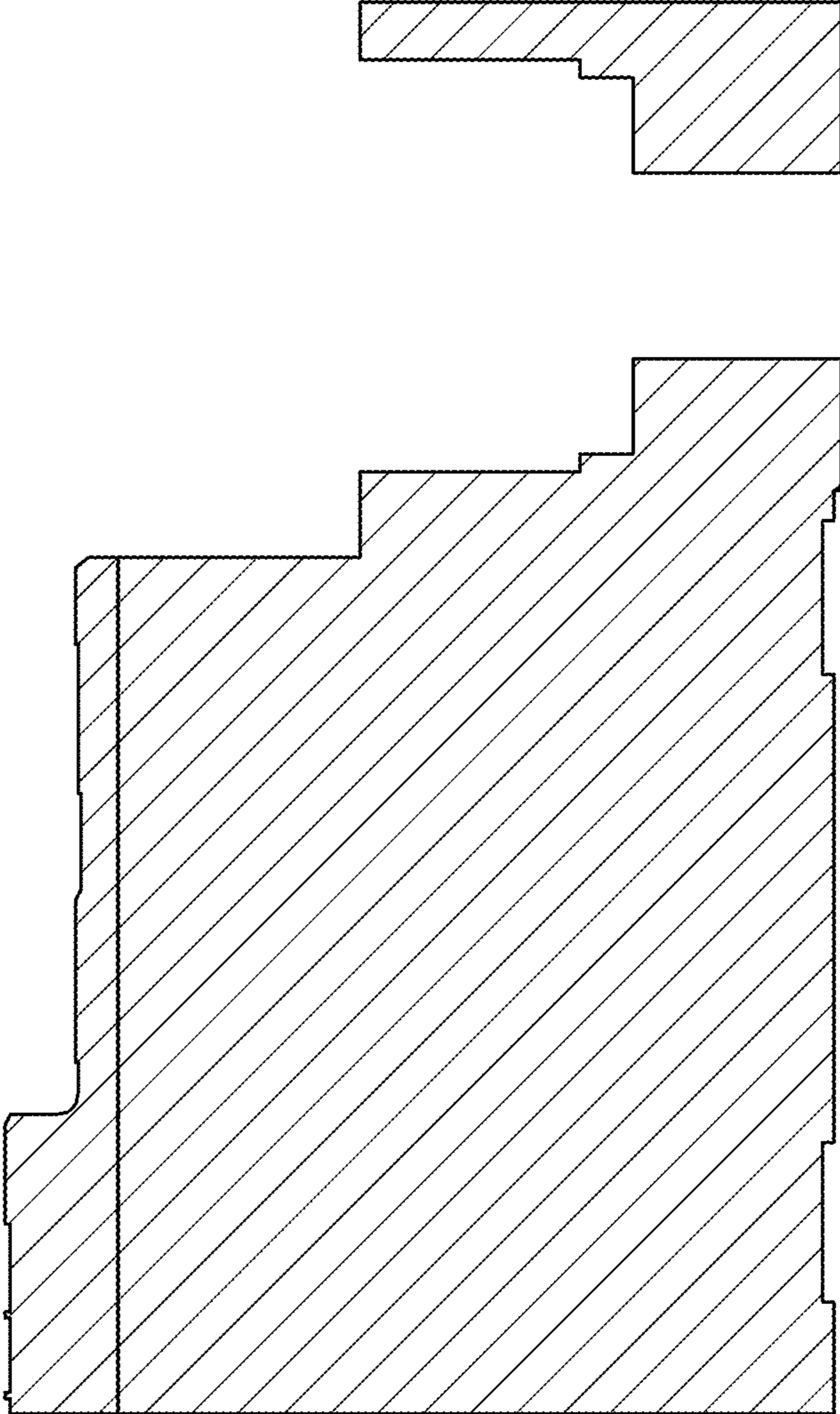


FIG. 8

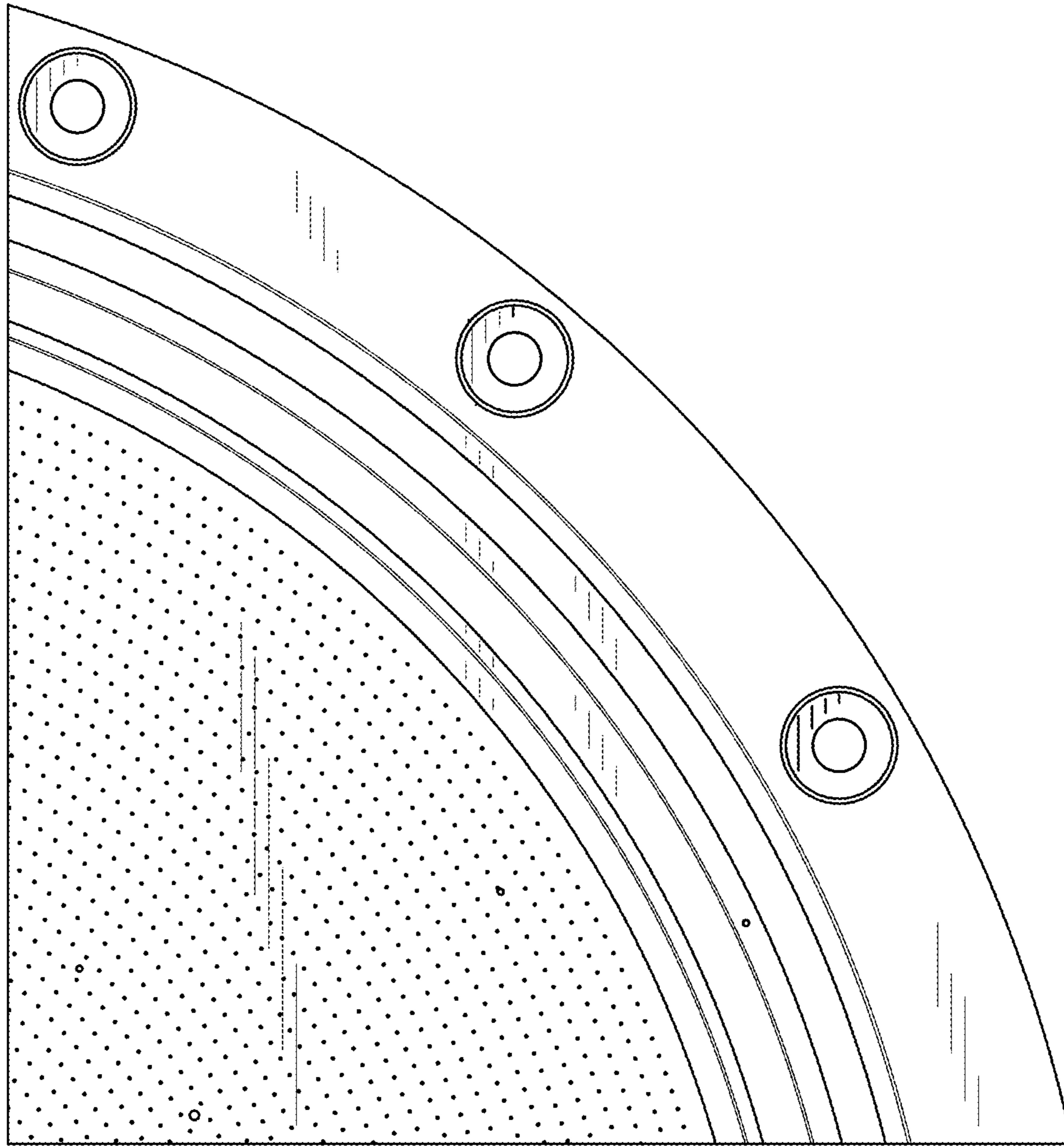


FIG. 9